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PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 3723**

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Makoto KOBAYASHI et al.

Group Art Unit: 3723

Application No.: 09/830,434

Examiner: H. Shakeri

Filed: April 26, 2001

Docket No.: 109352

For: POLISHING PAD AND POLISHING METHOD FOR SEMI-CONDUCTOR WAFER

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the June 17, 2003 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**

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SEP 23 2003

TECHNOLOGY CENTER R3700